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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Yair EIN-ELI et al

Serial No.: 10/750,969

Filed: January 5, 2004

For: TEXTURING A
SEMICONDUCTOR MATERIAL
USING NEGATIVE POTENTIAL
DISSOLUTION (NPD)

Group Art Unit: 1742

Attorney Docket: 27054

Examiner: Nicholas A. Smith

**Mail Stop: Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450**

ELECTION

Sir:

This is in response to the United States Patent and Trademark Restriction Office Action mailed February 2, 2007, which response is being made on or before March 2, 2007, and for which no extension of time fee is due.

Applicants hereby elect **Group I, namely Claims 1-92**, drawn to a method for texturing a semiconductor material.

Applicants reserve the right to file, at a later date, additional divisional applications claiming priority from the present application which are directed to the non-elected Group.

Respectfully submitted,

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Date: March 1, 2007